

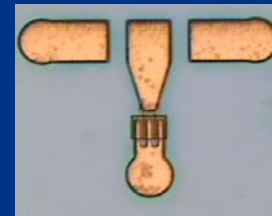
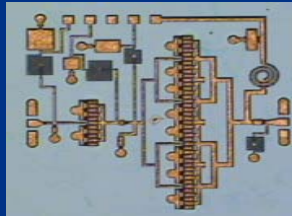
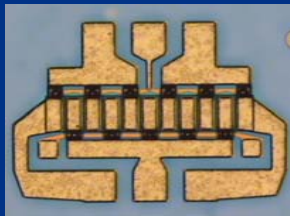


SiC-based microwave devices and circuits

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Outline

- SiC MESFET
- SiC MMIC
- AlGaN/GaN HEMT
- AlGaN/GaN MMIC
- Summary

Why SiC AlGaN-GaN

The WBG high frequency electronics is *emerging* i.e. due to the extreme properties of the material, components with extreme properties can be realized which can have an enormous impact on systems regarding

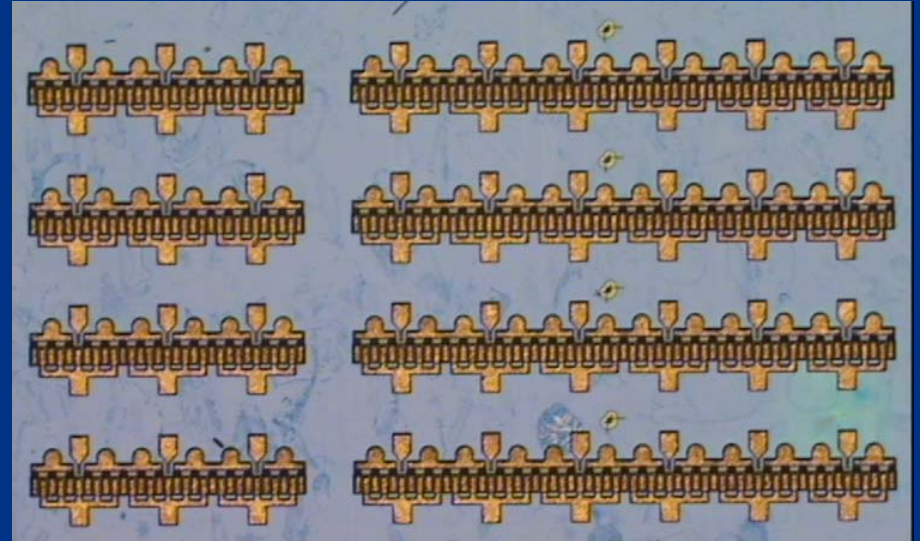
- Linearity wireless communication
- Ruggedness radar/space applications (high lifetime)
- Output power radar systems
- Bandwidth radar systems and communication

SiC material system more mature than AlGaN/GaN

MESFETs

New generation MESFET double recess, field plate

- 7.8 W/mm @ 3 GHz
- $V_{BR} = 200$ V
- $I_{DSS} > 500$ mA/mm
- 70% drain efficiency in class AB operation @ 3 GHz



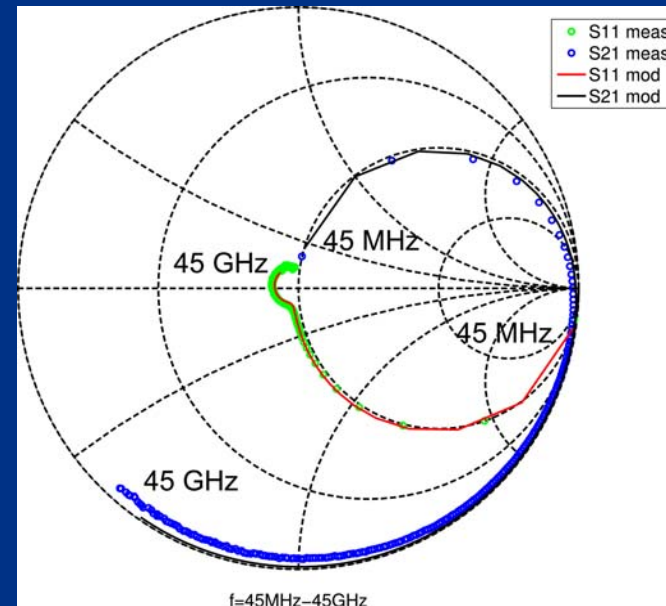
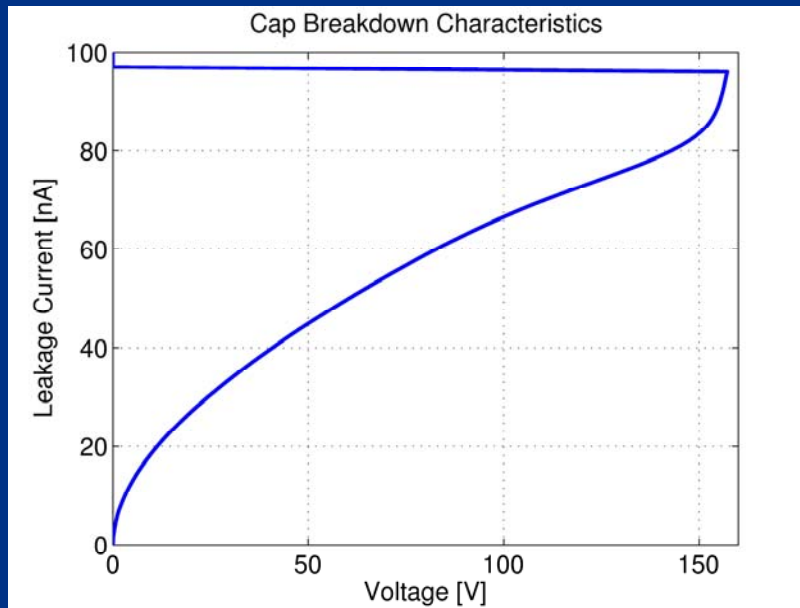
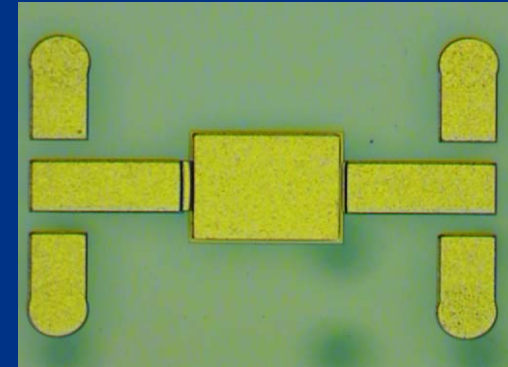
Via-hole grounded 3mm and 6mm SiC MESFETs

μ -strip MMIC Process Modules

- MESFETs
- MIM Capacitors
- Spiral Inductors
- Thin Film Resistors (TFRs)
- Via-holes

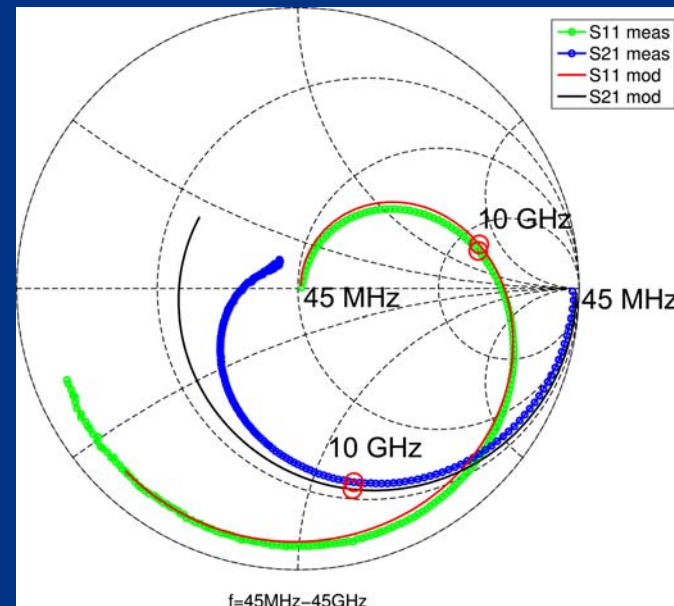
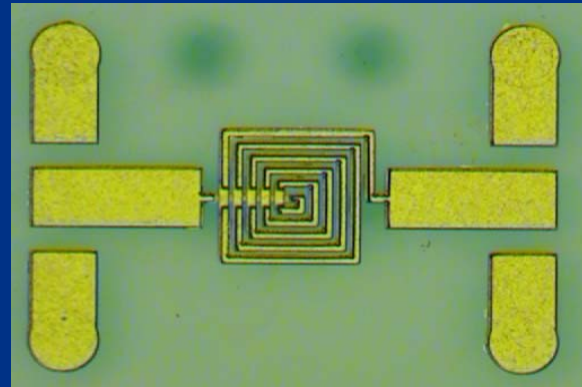
MIM Capacitors

- $\text{SiO}_2/\text{Si}_3\text{N}_4$ stack
- $\text{CPUA} = 200$
 pF/mm^2
- $V_{\text{BR}} = 150 \text{ V}$



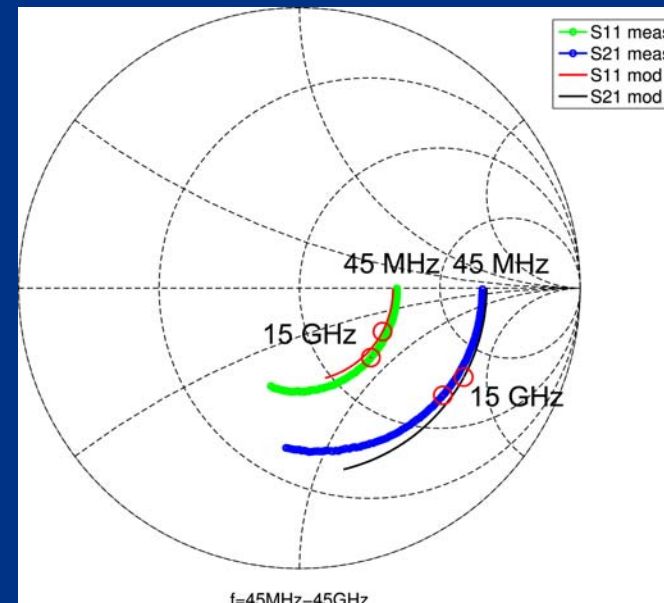
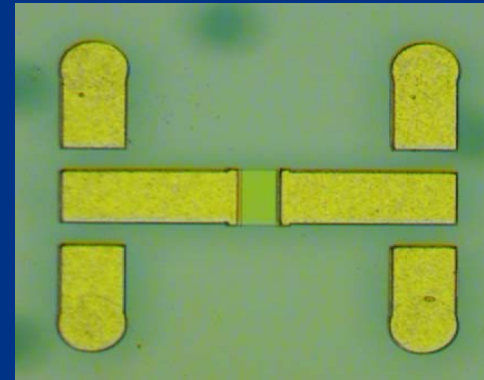
Spiral Inductors

- Air-bridged spiral inductors
- 0.4-3.6 nH
- $I_{\text{MAX}} > 1 \text{ A}$



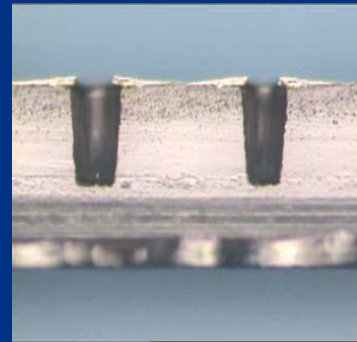
Thin Film Resistors (TFRs)

- Reactively sputtered TaN
- Sheet resistivity $45\Omega/\square$

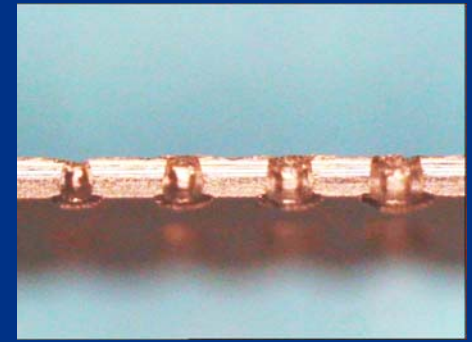


Via-holes

- Lapping
- Fluorine based (NF_3) ICP etching
- Excellent geometrical properties
- Front side compatible



A 140 μm deep via-hole



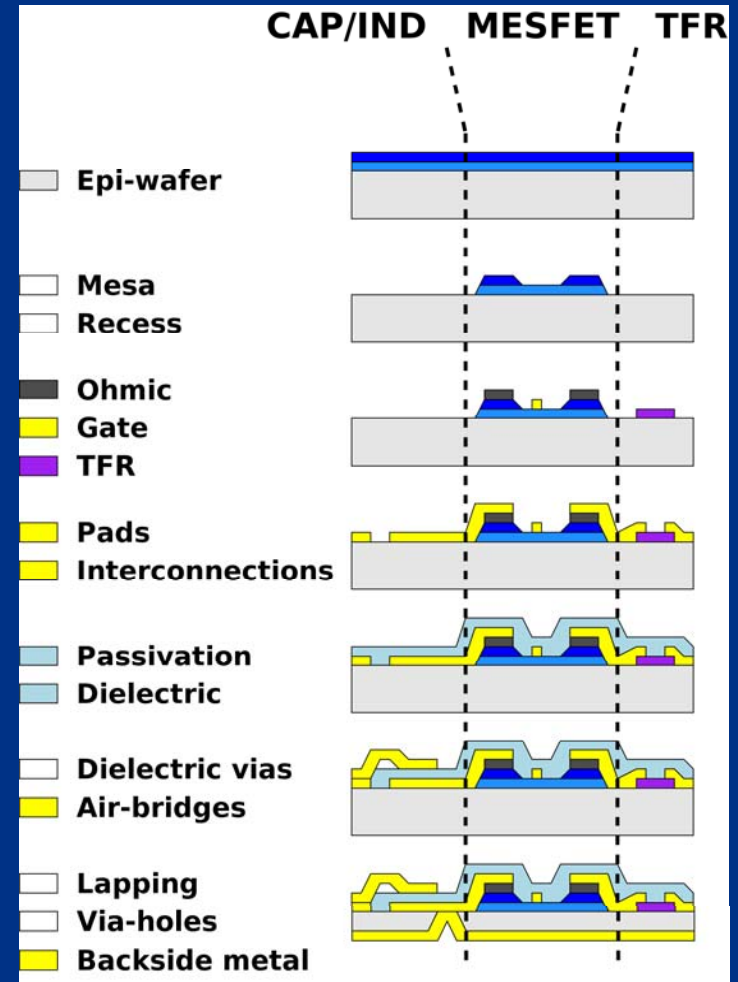
Through wafer via-holes



80 μm diameter through wafer via-holes on an MMIC chip

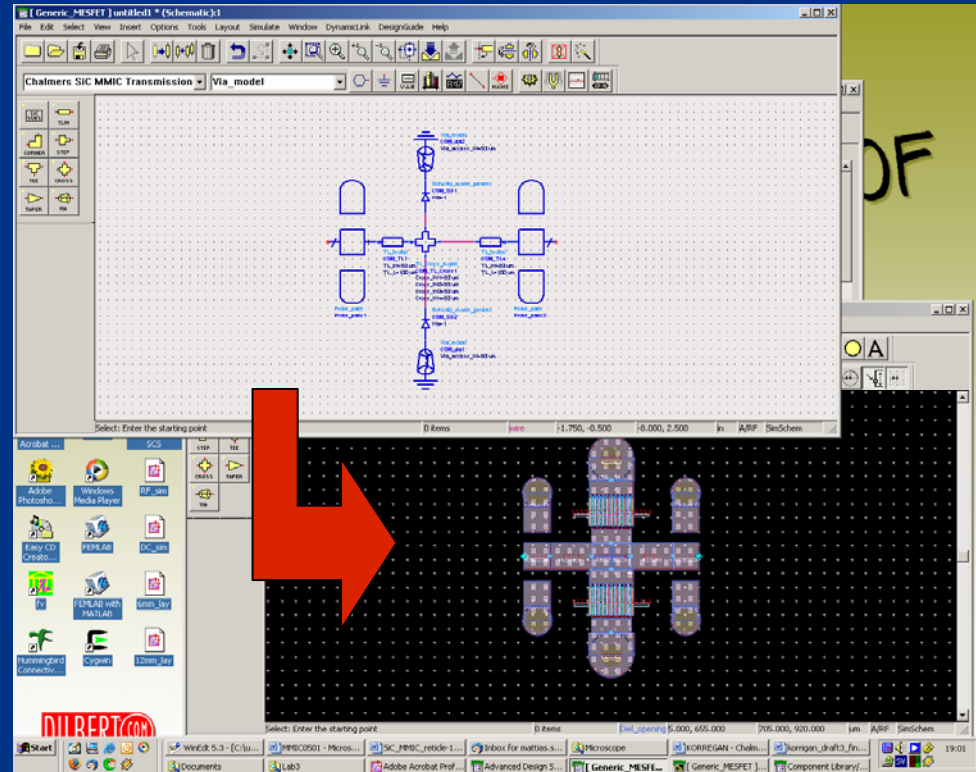
Process Sequence

- 13 mask steps
- Epi-wafer based
 - no implantation or CVD regrowth
- 3 weeks turnaround time



Modeling and Integration

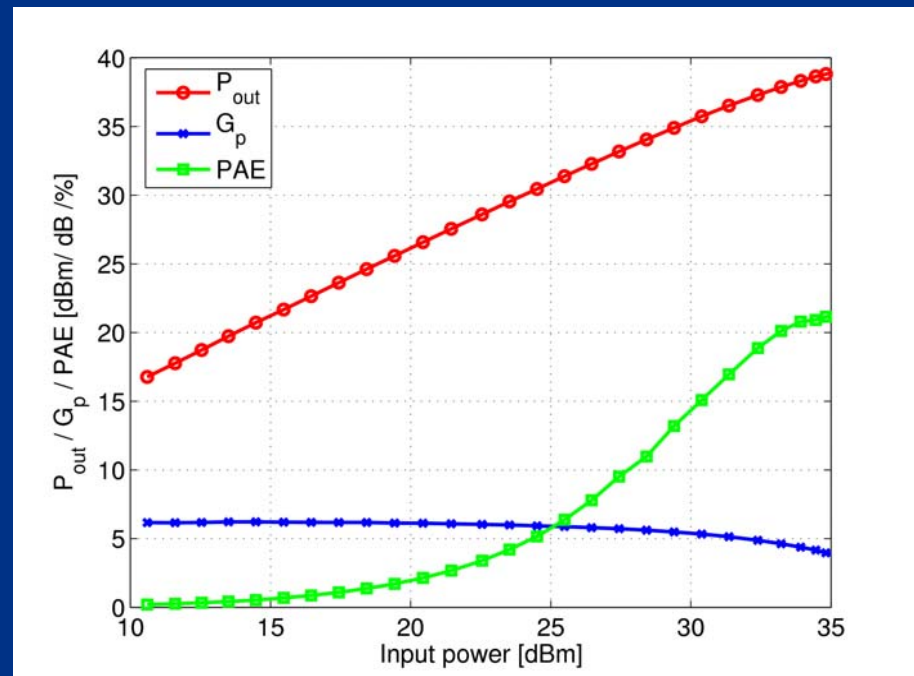
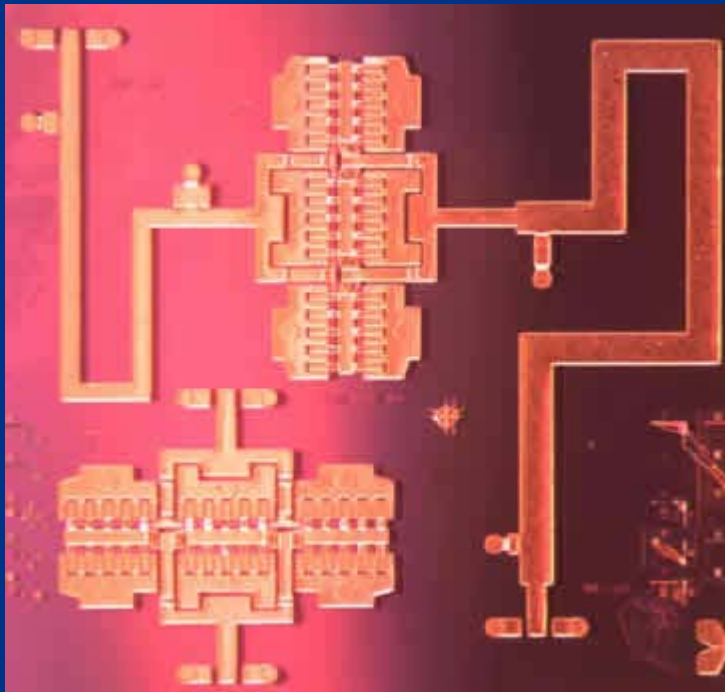
- Built in scaleable models in ADS
- Design kit implemented
- Auto layout
- DRC
- Scalable MESFET model under development



First circuit demonstrators 1/(3)

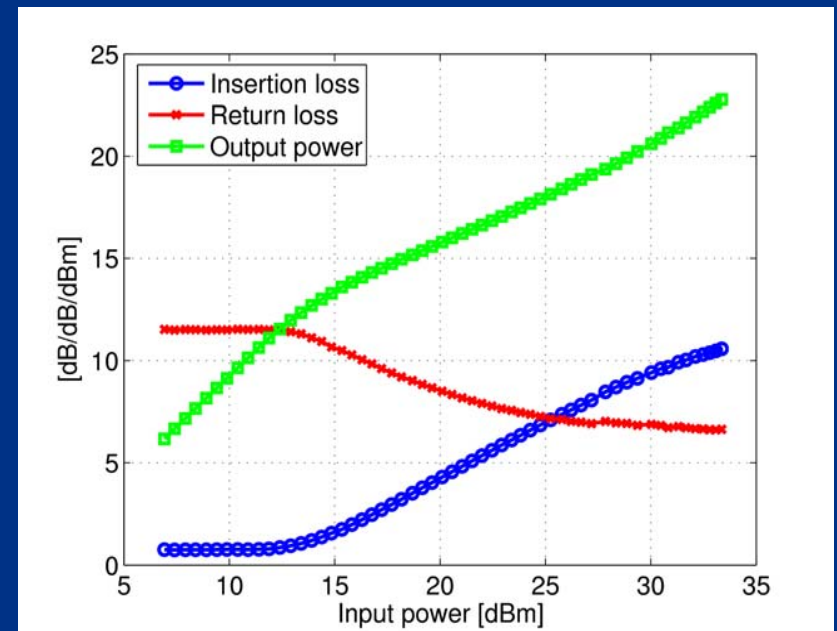
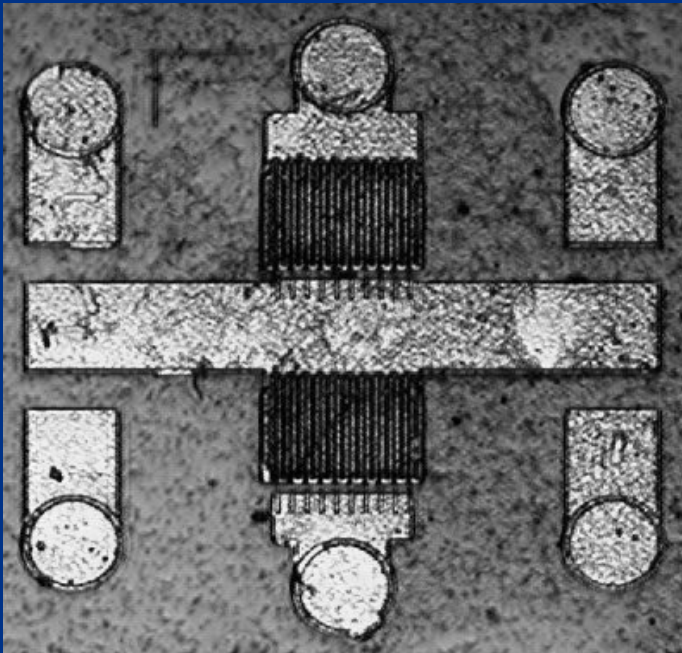
(using previous generation of MESFET)

- Simple narrowband S-band power amplifier
 - 8 W (pulsed) @ 3 GHz



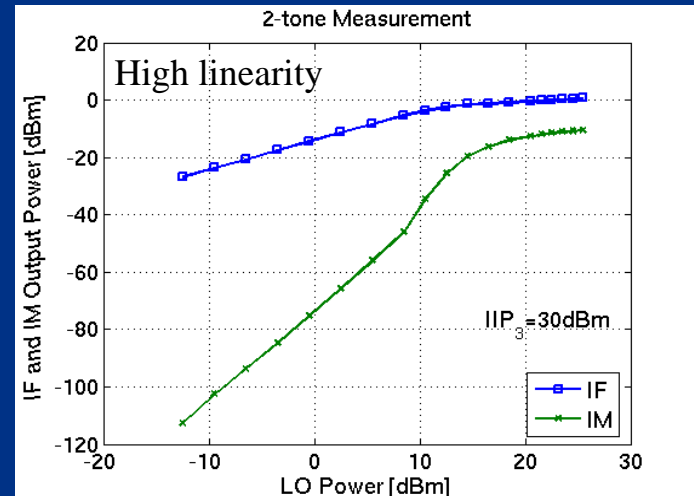
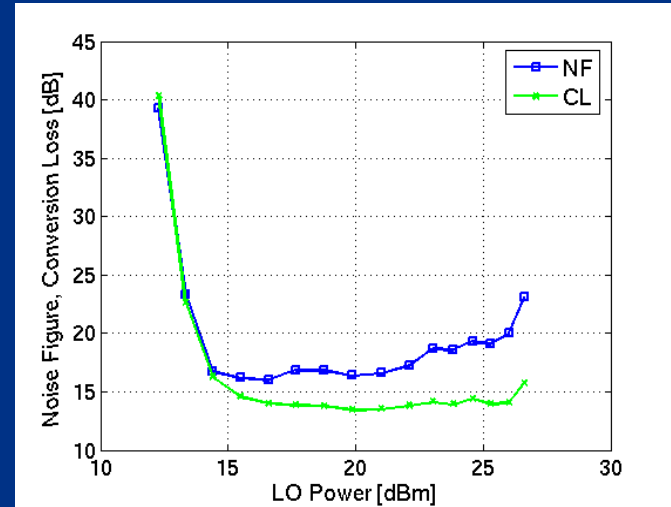
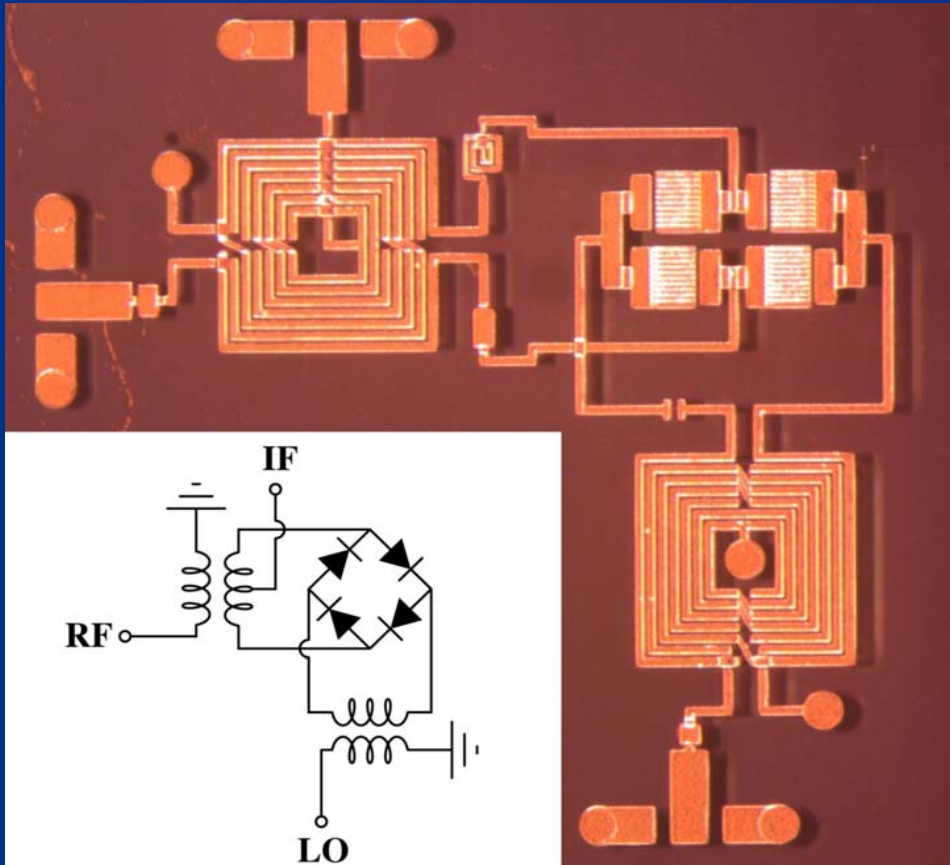
Circuit Demonstrators 2/(3)

- BtB Schottky diode power limiter for radar receiver protection
 - insertion loss < 1 dB @ 3-4 GHz



Circuit Demonstrators 3/(3)

Double balanced S-band Schottky mixer



$f_{LO} = 3\text{GHz}, f_{RF} = 3.3\text{GHz}, f_{IF} = 300\text{MHz}$

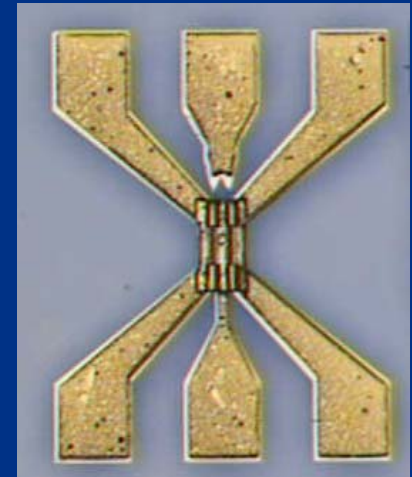
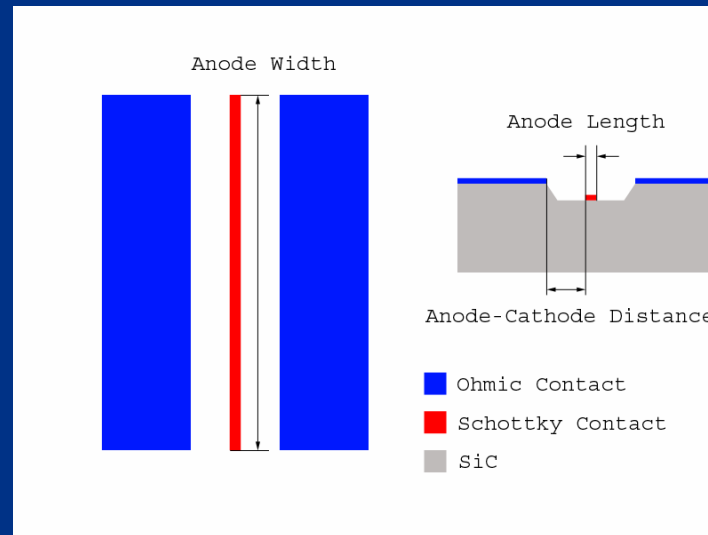
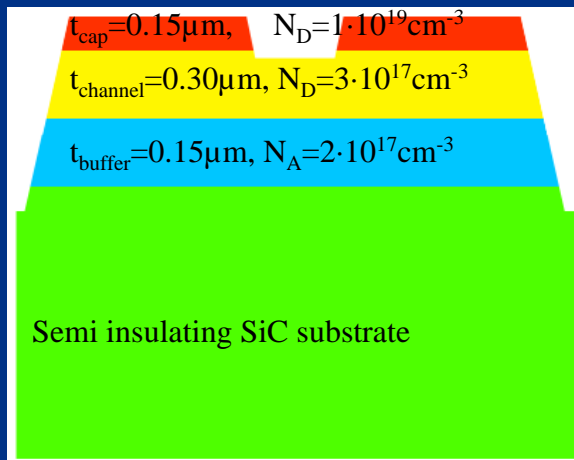
$CL_{\min} = 13\text{dB}, NF_{\min} = 16\text{dB}$

SiC planar Schottky

Goal: High f_c at high power.

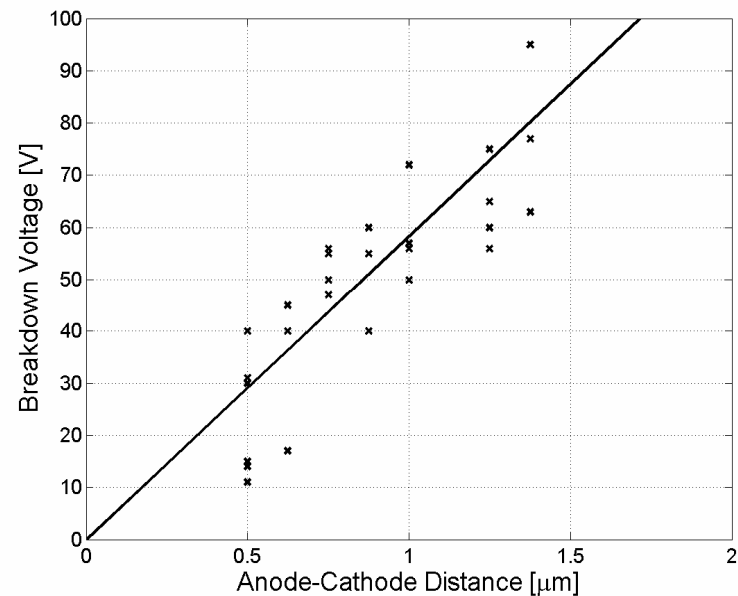
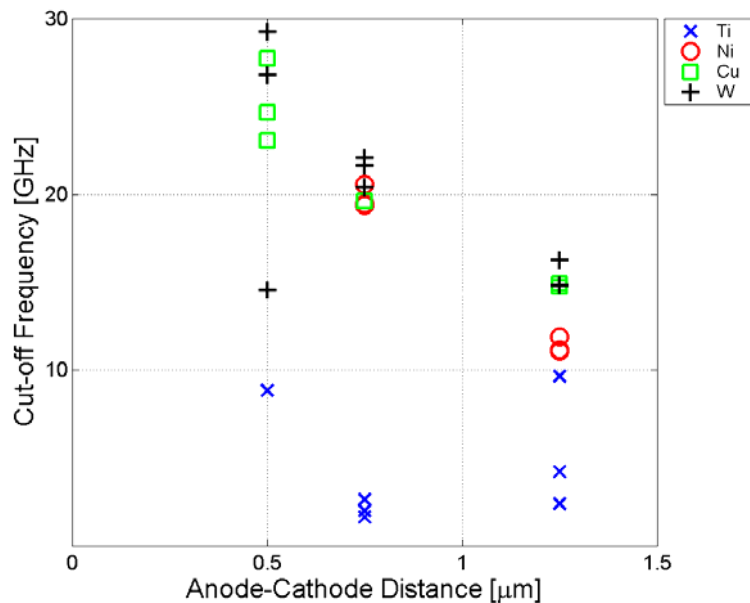
Compatible with MMIC process.

Planar design:



Device Results

Schottky Metal	Ti	Ni	Cu	W
Max Cut-off Frequency, $f_{c,max}$ [GHz]	9,6	20,6	27,7	30,8
Barrier height, ϕ_B [eV]	1,0	1,4	1,5	1,3
Ideality Factor, η	1,9	1,2	1,7	1,5



Summary and Conclusions

- Complete SiC MMIC process module library
- High voltage and power compliant passives
- Design kit implemented
- Circuit demonstrators successfully realized

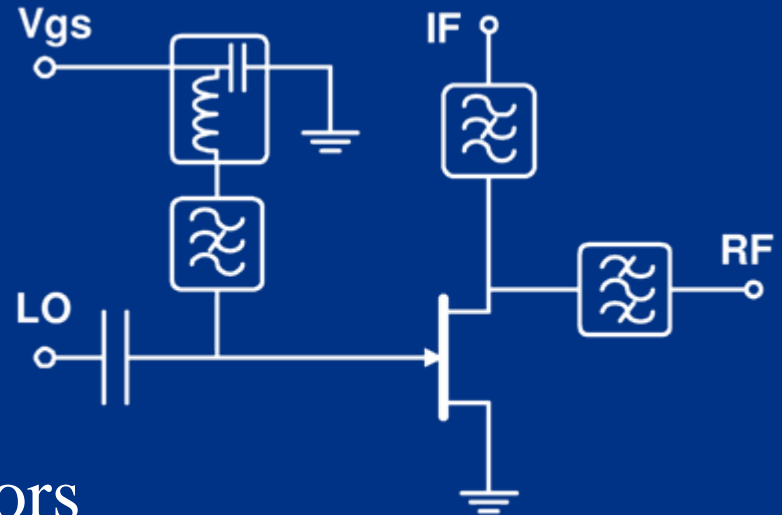
Next:

New generation MESFET, including NL model extraction

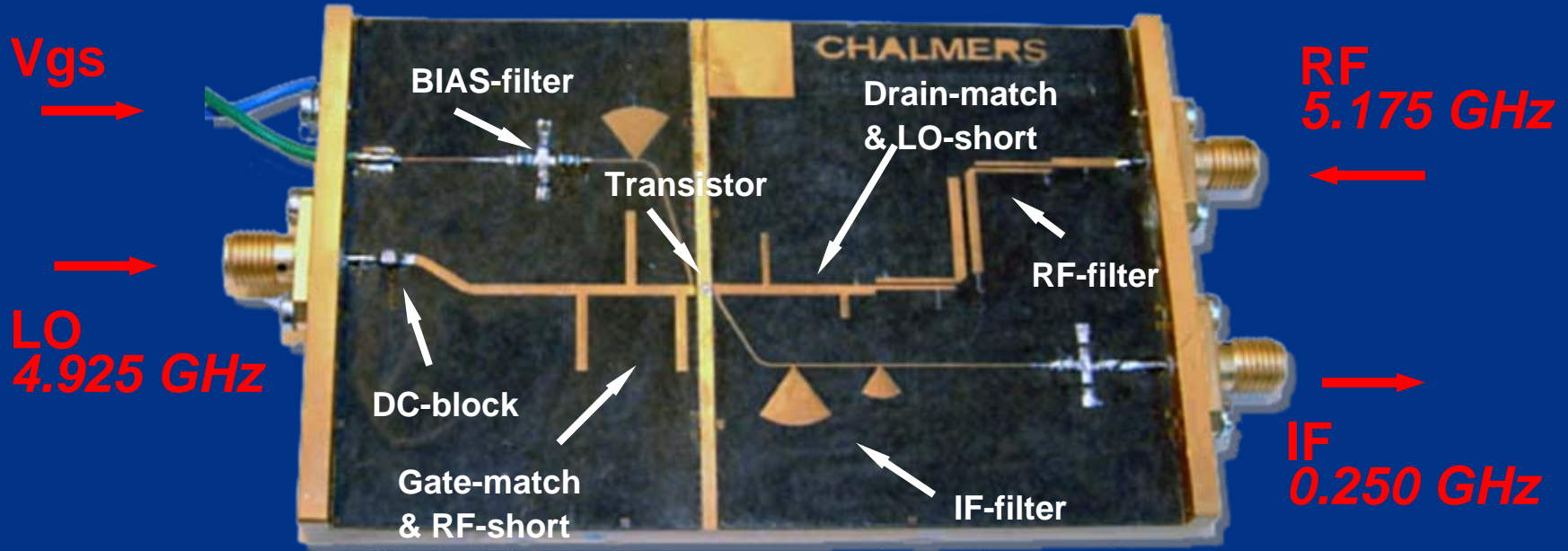
Other circuits : resistive mixer results

Why WBG mixer ?

- High linearity /LO-power
- Highly rugged
- ‘Proof of concept’ demonstrators made at CTH
- PhD student Kristoffer Andersson



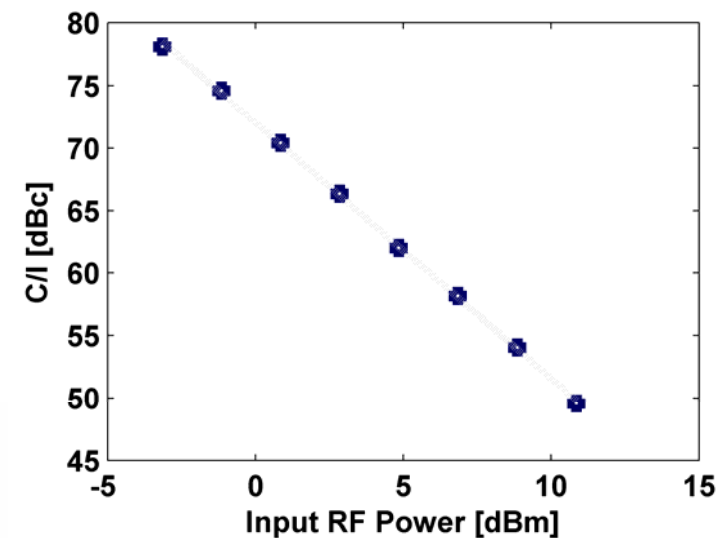
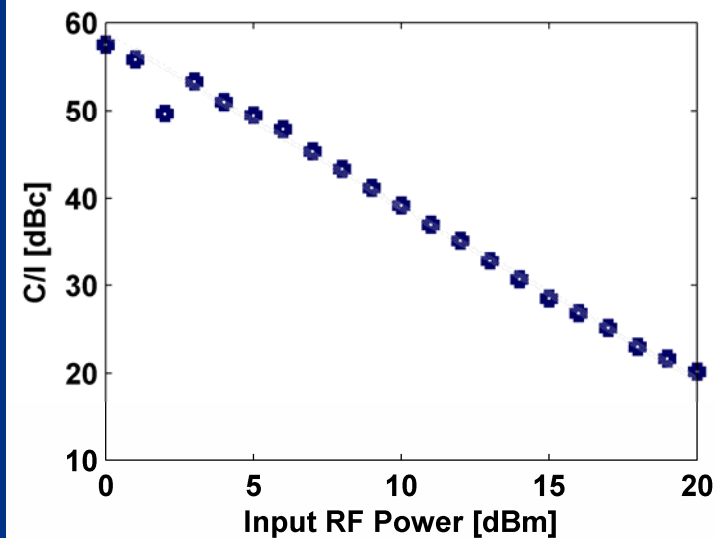
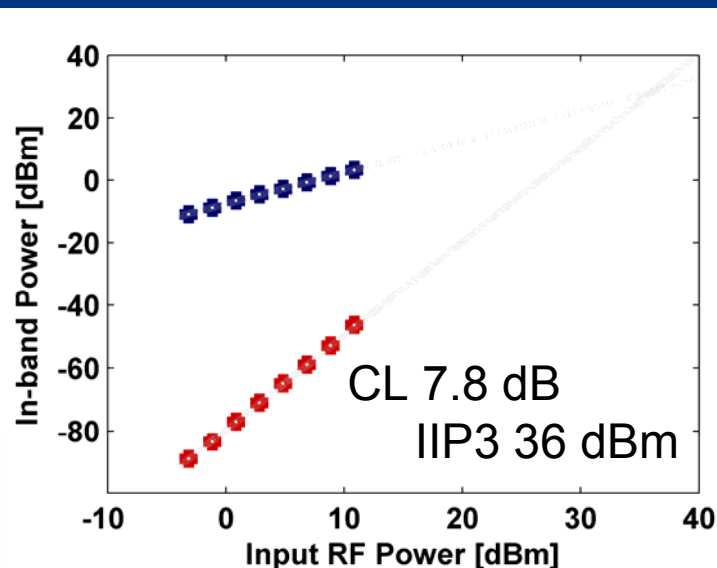
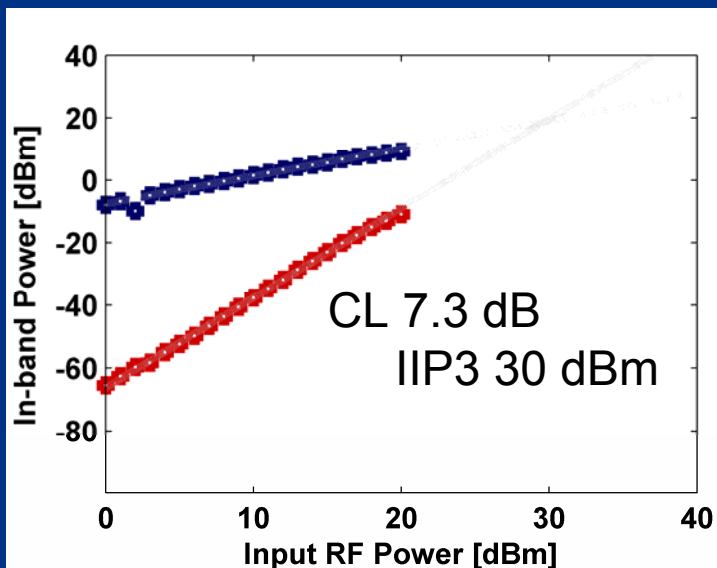
C-Band Resistive Mixer:



- Single-Ended
- Hybrid/Microstrip
- Narrowband

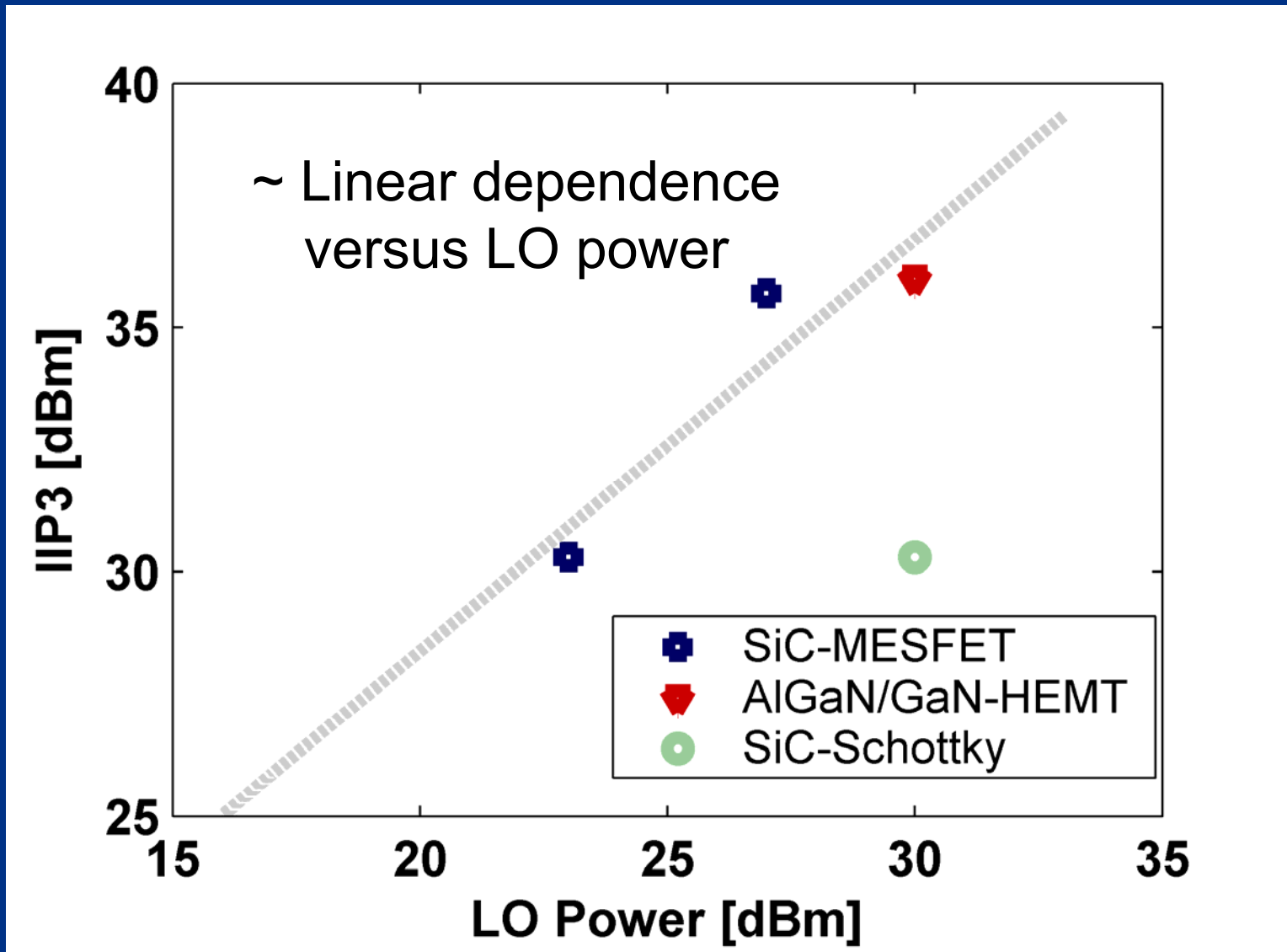
SiC-MESFET @23 dBm LO

AlGaIn/GaN-HEMT @ 30 dBm LO



* RF input limited due to instrumentation failure

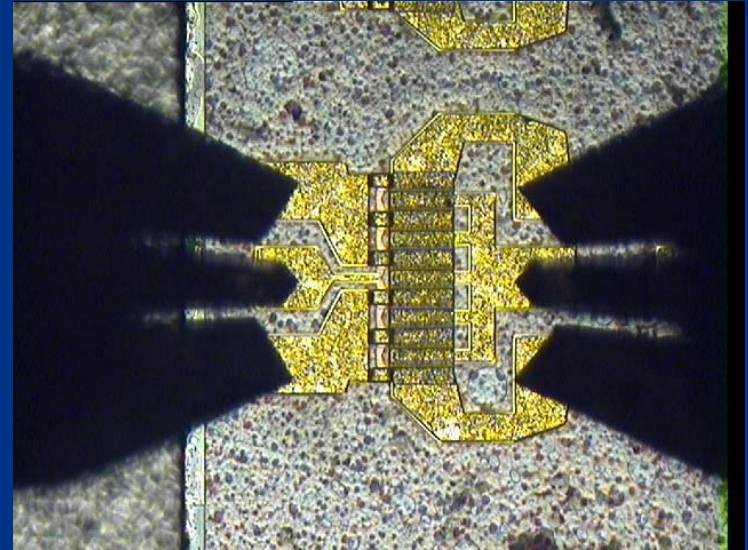
Chalmers WBG mixers so far:



HEMTs

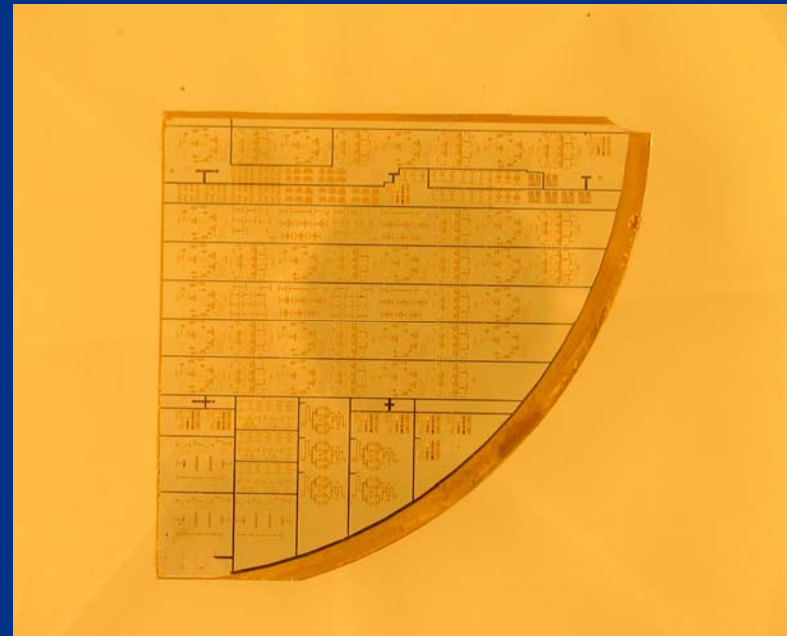
HEMTs w/o field plate

- 9.7 W/mm @ 3 GHz
- $I_{DSS} = 1.2$ A/mm
- 75% drain efficiency in class C operation @ 3 GHz



AlGaIn/GaN MMIC

- Fall 2006
 - KORRIGAN
- Preliminary process run
 - Passive modeling
 - Experimental circuits



Summary

- SiC MESFETS with power densities of 7.8 W/mm @ 3 GHz
- SiC MESFET microstrip MMIC process demonstrated 2005 including three circuit demonstrators
- New circuits based on our high η/P_{dens} MESFET process is under development
- AlGaN-GaN HEMT on SiC process with 9.4 W/mm (without fieldplate) demonstrated
- AlGaN/GaN MMIC demonstrators to come during fall 2006

People

- Kristoffer Andersson, **Ph.D. Student**
 - Models, Characterization, and Demonstrator Circuits
- Fredrik Allerstam, **Ph.D. Student**
 - SiC MOSFET processing
 - SiC oxide growth
- Guðjón Guðjónsson, **Ph.D. Student**
 - SiC MOSFET processing
- Martin Fagerlind, **Student**
 - GaN MMIC processing
- Mattias Südow, **Ph.D. Student**
 - SiC and GaN MMIC
 - SiC Schottky Diodes
- Hans Hjelmgren, Ph.D.
 - Simulations
- Per-Åke Nilsson, Ph.D.
 - Process line responsible
 - processing of SiC MESFET, MOSFET
- Niklas Rorsman, Ph.D.
 - Project leader (SiC MESFET/GaN HEMT), processing and characterization
- Einar Ö. Sveinbjörnsson, Ph.D.
 - Project leader SiC MOSFET
- Herbert Zirath, Professor
 - Group leader

Pulsed Load-pull device evaluation

- Load and source tuners, 0.8 – 18 GHz, 8-50, V and W band
- Pulsed VNA, 0.5-20 GHz
- Pulsed power meter
- Pulsed IV, 100 V 4 A
- 400 W bias supply
- $P_{IN} = 30 \text{ dBm}$, 2-8 GHz

